## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:

Dwight and David Zuck

Assignee:

Quantum Global Technologies, LLC

Title:

"SYSTEM FOR REMOVING CONTAMINANTS FROM

SEMICONDUCTOR PROCESS EQUIPMENT"

Serial No.:

Unknown

Filed:

July 18, 2003

Examiner:

Unknown

Tel:

Unknown

Docket No.:

Z-001-2C

Art Unit:

Unknown

Mail Stop Patent Application Commissioner For Patents P.O. Box 1450 Alexandria, VA 22313-1450

## INFORMATION DISCLOSURE STATEMENT

Sir:

Pursuant to 37 C.F.R. §1.56, §1.97 and §1.98, Applicants bring the 39 documents listed on the enclosed forms PTO-1449 to the Examiner's attention in the above-captioned application. Citation of the listed documents shall not be construed as:

- 1. an admission that the documents are necessarily prior art with respect to the instant application;
- 2. a representation that a search has been made; or
- 3. an admission that the information cited is, or is considered to be, material to patentability as defined in §1.56(b).

Applicants are not providing copies of the documents listed on forms PTO-1449 because the documents are cited in prior applications (Serial Numbers 10/288,404 and/or 09/504,299), the benefit of which is relied upon under 35 U.S.C. §120.

I hereby certify that this correspondence is being deposited with the United States Postal Service as "Express Mail" on the date indicated below and is addressed to: Mail Stop Patent Application, Commissioner for Patents, P.O. Box 1450, Alexandria, VA /22313-1450.

July 18, 2003 Date

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Laurie Moreno

Express Mail No.: ET203108735 US

Respectfully submitted.

Arthur J. Behiel

Attorney for Applicants

Reg. No. 39,603

U.S. Depar	tment	of Commerce	Patent and T	Trademark Office	Applicat	ion No.: Ur	nknown			
U.S. Department of Commerce, Patent and Trademark Office					Filing date: July 18, 2003					
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Inventors: Dwight and David Zuck					
(Use several sheets if necessary)						Group Art Unit: Unknown				
"SYSTEM FOR REMOVING CONTAMINANTS FROM SEMICONDUCTOR					Examiner name: Unknown					
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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